

Platinized or PZT Coated Product Specifications

Product: PZT or PNZT Coated Wafers with Platinum Bottom Electrodes

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Author: Joe Evans

Description:

The product starts with a silicon wafer with 0.5 μ of thermal silicon dioxide on its surface. The customer may specify the wafer type for purchase by Radiant or the customer may supply the wafers. Otherwise, Radiant generally uses 550 μ thick <100> boron doped silicon wafers with 10 Ω -cm resistivity. Radiant deposits a 400 \AA layer of titanium dioxide on the surface of the silicon dioxide followed by 1500 \AA of pure platinum. The platinum is not patterned. Radiant then deposits either 20/80 PZT up to 3700 \AA thickness or 4% niobium doped 20/80 PZT (PNZT) up to 1 μ thickness on the platinum surface using an MOD technique. PNZT sintering takes place at 650 $^{\circ}$ C.

The customer may elect to supply wafers having mechanical features in or under the silicon surface. The primary requirement is that the surface of the wafer be silicon dioxide. The maximum temperature seen by the wafers during processing is 850 $^{\circ}$ C.

It is possible to deposit the platinum/PZT or platinum/PNZT on both sides of double side polished wafers. In this case, the bottom electrode is deposited on both sides first followed by the PNZT on one side and closing with the PNZT on the other.

Thin silicon wafers may be used in place of the standard 550 μ thick silicon wafers but allowances must be made for breakage during processing.